

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Application of: Wolfgang M.J. Hofmann and ]  
Noel C. MacDonald )  
 )  
Application No. Division of 10/021,311 ) Group:  
 )  
Filed: Even date herewith ) Examiner:  
 )  
For: MULTIPLE-LEVEL ACTUATORS )  
AND CLAMPING DEVICES )

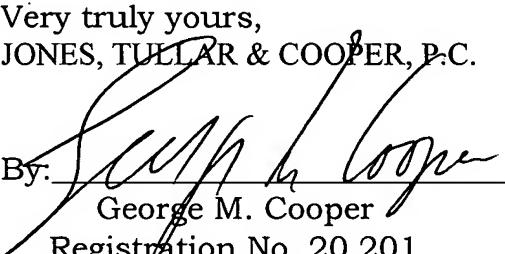
**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 CFR 1.97 and 1.98, applicant hereby makes of record the documents listed on the attached PTO form 1449. A copy of each document may be found in copending parent application No. 10/021,311, pending in Group Art Unit 1772, with the exception of the newly-cited article entitled "Deep Silicon RIE with Profile Control" dated October 23, 1997.

Very truly yours,  
JONES, TULLAR & COOPER, P.C.

By: 

George M. Cooper  
Registration No. 20,201

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October 7, 2003

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## Sheet

of 1

***Complete if Known***

Application Number	T.B.A.
Filing Date	Even Date Herewith
First Named Inventor	Wolfgang M.J. Hofmann
Group Art Unit	1772
Examiner Name	
Attorney Docket Number	Hofmann

## U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code <sup>2</sup> (if known)			
		5,198,390		MacDonald	03/03/1993	
		5,199,917		MacDonald	04/06/1993	
		5,235,187		Arney	08/10/1993	
		5,287,082		Arney	02/15/1994	
		5,316,979		MacDonald	05/31/1994	
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## FOREIGN PATENT DOCUMENTS

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<p>Examiner Name</p>					
<p>Attorney Docket Number</p>		<p>Hofmann</p>			
Sheet	1	of	1		

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**OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS**

Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
		CHANG, T.H.P., Kern, D.P., Muray, L.P.; Microminiaturization of electron optical systems; J. Vacuum Science & Technology B, vol. 8, pp. 1698-1705, 1990	
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		CHEN, L.-Y., MacDonald, N.C.; Surface micromachined multiple level tungsten microstructures; Technical Digest Solid-State Sensor & Actuator Workshop; pp. 99-102, 1994
		HOFMANN, W., Lee, C.S., MacDonald, N.C.; Monolithic three-dimensional single-crystal silicon microelectromechanical systems; Sensors & Materials, vol. 10, pp. 337-50, 1998
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		HOWE, R.T., Boser, B.E., Pisano, A.P.; Polysilicon integrated microsystems: technologies and applications; Sensors & Actuators A, vol. 56, pp. 167-177, 1996
		RODGERS, M.S., Sniegowski, J.J.; 5-Level Polysilicon Surface Micromachine Technology: Application to Complex Mechanical Systems; Solid-State Sensor & Actuator Workshop, Hilton Head Island, SC, 1998
		AYON, A.A., Lin, C.C., Braff, R.A. and Schmidt, M.A.; Etching Characteristics and Profile Control in a Time Multiplexed Inductively Couples Plasma Etcher; Solid-State Sensor and Actuator Workshop, Hilton Head, SC, 1998

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